## Amendments to the Claims:

The following listing replaces all prior listing of claims in the application.

## Listing of Claims

1. (Currently amended) A lithographic method comprising the pressing of a substrate, the method comprising:

preparing a substrate surface by forming a composite layer on the substrate, wherein forming the composite layer comprises forming an internal sub-layer of curable material and curing the internal sub-layer, and forming an external sub-layer adjacent to the cured internal sub-layer;

pressing a mold comprising a pattern of recesses and protrusions, wherein the protrusions of the mold penetrate into the external sub-layer until the protrusions contact the internal sub-layer;

performing at least one etching process in which the composite layer is etched until portions of a surface of the substrate have been exposed; and

etching the substrate using an etching pattern defined by the mold pattern

wherein the preparation step further comprises forming an internal sub-layer or curable material and curing the internal sub-layer, and forming an external sub-layer adjacent to the internal sub-layer, and

wherein the pressing step further comprises penetrating the protrusions of the mold into the external sub-layer until the protrusions contact the internal sub-layer.

2. (Currently amended) The method according to claim 1, wherein <u>forming</u> the internal sub-layer <u>is formed comprises forming the internal sub-layer in contact with the substrate surface and <del>wherein, during the performing at least one etching step, comprises removing the internal sub-layer is removed in the regions defined by recesses of formed in the external sub-layer, and, wherein during etching the substrate</u></del>

<u>comprises</u> etching <u>step</u>, <u>regions of</u> the substrate <u>is etched through exposed by</u> the recesses.

- 3. (Currently amended) The method according to claim 1, wherein <u>forming</u> the internal sub-layer and the external sub-layer comprise <u>forming</u> the same material.
- 4. (Currently amended) The method according to claim 1, wherein curing the internal sub-layer comprises a heat treatment of heating the internal sub-layer at a temperature higher than its a curing temperature of the internal sub-layer, and wherein the pressing step the mold comprises is carried out pressing at a pressing temperature higher than a glass transition temperature of the external sub-layer.
- 5. (Currently amended) The method according to claim 1, wherein <u>forming</u> the <u>internal sub-layer of a curable material comprises forming a polymer.</u>
- 6. (Currently amended) The method according to claim 1, wherein <u>forming</u> the <u>internal sub-layer of a curable material comprises forming a resin that is formulated configured to be cross-linked.</u>
- 7. (Currently amended) The method according to claim 5, wherein <u>forming</u> the <u>internal sub-layer of a curable material comprises forming</u> one of a negative resin or a positive resin.
- 8. (Currently amended) The method according to claim 1, wherein <u>forming</u> the internal sub-layer <u>has-comprises forming a sub-layer having a</u> thickness of 0.01 micron to 1 micron.
- 9. (Currently amended) The method according to claim 1, wherein <u>forming</u> the <u>external sub-layer comprises forming</u> the <u>thickness of the external sub-layer is to a thickness</u> less than the <u>a</u> depth of the pattern <u>of recesses</u>.
- 10. (Currently amended) The method according to claim 6, wherein <u>forming</u> the curable material <u>a resin</u> comprises <u>forming</u> one of a negative resin or a positive resin.

## 11. (New) A lithographic method comprising:

forming a first layer on a substrate, the first layer comprising a curable material, and curing the first layer;

forming a second layer on the first layer, the second layer comprising a deformable material;

pressing a mold against the second layer, wherein protrusions of the mold form recesses in the second layer that expose portions of the first layer;

etching the exposed portions of the first layer using the second layer as an etch mask, and exposing surface regions of the substrate; and etching the surface regions of the substrate.